

ABSTRACT

A vacuum pump, a vacuum pump controller, and a remote controller are provided that can reduce the workload of users and field service engineers. A vacuum pump 10 includes a turbomolecular pump 100 that exhausts gas inside a semiconductor manufacturing apparatus X, and a controller 200 that performs control on the turbomolecular pump 100. The controller 200 includes a remote signal receiving means that receives a command signal from a remote controller 300, which remotely controls the turbomolecular pump 100, and changes a setting relating to an operating specification of the turbomolecular pump 100 on the basis of the command signal received by the remote signal receiving means.

10 [Selected Figure] Fig. 1